

Amendments To The Specification:

Please replace the paragraph beginning at page 8, line 24 and ending on page 9, line 5, with the following rewritten paragraph:

--Fixedly mounted off-stage is a single beam dynamic interferometer (or interferometer subsystem) **10** for measuring angular rotation of stage **16**, and thus planar mirror reflecting surface **51**, about the y and z axes as stage **16** translates in the y-direction. To accomplish this, dynamic interferometer **10** is structured and arranged in the manner described in aforementioned PCT Patent Application No. PCT/US00/10297 filed May 5, 2000 and entitled " Interferometry Systems Having a Dynamic Beam-Steering Assembly For Measuring Angle and Distance" by Henry A. Hill which was published as WO 00/66969 and in U. S. Patent No. 6,271,923, the contents of which is incorporated herein by reference in its entirety. As described in that application, mirrors are provided with beam steering capability by which bothersome stage rotations are measured to provide feedback signals that are used to maintain beams on paths that are normal to the mirrors. Here, the return beam component of beam **12** is monitored, and its angle is measured via interferometric apparatus such as that described in U.S. Patent Application No. 60/201,457 filed on May 3, 2000 in the name of Henry Allen Hill and entitled "Apparatus And Method(s) For Measuring And/Or Controlling Differential Paths Of Light Beams", now Application No. 09/842,556 filed on April 26, 2001 with title "Dynamic Angle Measuring Interferometer" and Published on March 21, 2002 as US-2002-0033951-A1, the entirety of which is incorporated herein by reference.--